X ray analysis in the TEM and SEM.



Iron oxide coated glass beads in Quanta 3D SEM using drift controlled Noran EDS Jeff Nason environmental engineering group, OSU

Peter Eschbach



Terminology

- X ray analysis in SEM is the same as :
- EDS energy dispersive spectroscopy
- EDX* energy dispersive x ray
- WDS wavelength dispersive spectroscopy, higher resolution cousin of EDS.



Energy Dispersive spectra of Figure 1 with characteristic 124 -130 eV resolution.

Peter Eschbach



* Also EDAX which is a company name EDAX inc.

So, why would we bother with a lower resolution technique like EDS? When WDS is much higher resolution?

- WDS uses a crystal for the different energy, wavelength regions. You have to select the crystal before starting the analysis and there are 4 crystals. So, to get a complete scan you have to move the four crystals in and out of the x-ray path. This is slow compared with EDS.
- EDS detection systems are more efficient and require less beam and present less sample damage.
- EDS systems work well on standard SEM. WDS requires a special type of SEM called a microprobe. This type of SEM is tailored for high currents and fits the four crystals nicely in the system. An EDS-WDS system is available from Oxford, EDAX for conventional SEM, they are not commonly used but can be help in situations where overlap of peaks occurs, say Si(K) with Ta(L), or Mo(M) and S(K) lines.



Example of spectra illustrating the resolution improvements of WDS versus EDS using a stainless steel example.

From EDAX inc literature on Neptune system integrated EDS and WDS.

Peter Eschbach



Basics of detecting x-ray energy.

- When the X ray hits a detector it creates a shower of electrons or electron hole pairs. The total number of these individual events that comprises the show is proportional to the X ray energy.
- Remember that most X rays have thousands of electron volts kinetic energy. While it only takes about 1 eV to create a free electron in a silicon detector. So, we get hundreds to free electrons per x-ray!
- Higher energy x ray creates a bigger shower of electrons and these electrons. Lower energy x-rays create less of a shower.
- So, if we add up all the pulses in a shower we get an intensity proportional to x-ray energy. This allows us to identify the element that created the shower in the detector.



What pulses from an x ray look like in real time on a fast oscilloscope incident upon a silicon diode.

Peter Eschbach Oregon State University



Silicon drift detector SDD vs Lithium drifted Si(Li) detectors



Credit to Thermo Fisher for drawing, same detector as on OSU Quanta 3D

SDD detectors have always been very fast but suffered from non linear issues, distortion of low and high energy peaks. However, recent advances in design in last 10 years by PN Devices of Germany have made SDD the standard. PN devices probably makes 90% of SDD in world, all manufactures use them!



Lithium drifting Si(Li) makes the region between intrinsic semiconductor and so X ray hits it and charge separates to two plates, N and P side of junction. Capacitance is very high making it a slow detector but is highly linear.

Peter Eschbach



Multi Channel Analyzer, MCA, action and how it works

detected X ray

Hamper of magnetic steel balls Coil wraps around glass tube to shoot Channels are X ray energy magnetic balls into the correct channel or slot Drive current from pulse height of

The kicksorter, an early version of the Multi Channel analyzer, From Canberra, early MCA manufacturer. They credit Frazier Bronson with the original sketch

Peter Eschbach



The Modern Multi Channel Analyzer. We use the same concept as the mechanical kicksorter. But, now we electronically sort the X rays and place them in bins of increasing energy. Then every few milli seconds read them out and update a graphical interface, your SEM EDS spectra.

X ray pulses are integrated into a peak with a charge sensitive pre amp. That peak height is measured with an analog to digital converter or multi channel analyzer.



What pulses from an x ray look like in real time on a fast oscilloscope.

> Peter Eschbach Oregon State University



Pulses are electronically integrated with charge sensitive pre amp



The analog pulse at left is converted to a digital signal with the voltage of step proportional to pulse height. More energetic x rays give higher height

Pulse shaping time and resolution



Figure 7.5. Charge-to-voltage conversion process. (a) Representation of the detector chargeto-voltage converter and pulse-shaping amplifier from an electronics perspective. (b) Output of the charge-to-voltage converter after the detection of a series of x-ray photons.

From Goldstein, Newbury, Joy, Lyman, SEM and X-ray micro analysis.

We get more resolution in heights with longer shaping time but then are subject to artifacts such as pulse pile up or Sum peaks. So, we set shaping time to as low as possible to still resolve peaks. Or if we have an SDD (Silicon Drift Detector) we don't worry so much until currents are very large! Effect of shaping time, longer shaping time produces a higher resolution curve and pulls out weaker peaks like Carbon.



Figure 3: Illustration of voltage steps as a function of an absorbed X-ray. The noise fluctuations demonstrate the impact of noise and shaping time (top vs. bottom) on resolution.

Keith Thompson Thermo Scientific

Longer shaping time gives more accurate pulse height and tightens up distribution of energy!

- Shaping time is an important variable.
- Please play with shaping time.
- On the OSU Quanta 600 shaping times as low as 12 usec are necessary to resolve carbon peaks.



The larger the capacitor in our Operational amplifier feedback circuit, the longer the shaping time! For the Op. Amp and LF 355 JFET with low offset works nicely

Peter Eschbach



WDS process

- We do not use charge sensitive pre-amps and pulse height analysis to sort the energies.
- We use crystals that have carefully chosen lattice spacing's to diffract the x-rays into a simpler detector.
- Wavelength of Fe K alpha is solved at right, .194 nm.
- So, if we find a lattice with close to .2nm spacing we can get strong diffraction and detect elements near Iron with dramatic precision.



OSU Electron Microscopy Facility

Now that we have a basic idea of X ray detectors and the difference between EDS and WDS, let us talk about X ray processes. We will review some basic atomic physics at the undergraduate physics or chemistry level.

> Peter Eschbach Oregon State University



Stopping Power



- Stopping power is roughly how many KeV per micron a beam looses in traversing a sample, -dE/dx.
- In radiation dosimetry, study of how ionizing radiation damages material there is a rule of thumb for gamma rays and electrons: 10 keV per micron in tissue equivalent material (bone, water), so called lineal energy transfer. So, a one electron 10 keV/micron beam deposits 10 KeV in a one micron sample.
- A more detailed description is provided by the Bragg Curve shown at right based upon lineal energy transfer of 10 keV/micron and representing an approximate 30 keV electron beam upon atomic number close to Silicon.





5 keV electron beam striking Silicon



Simulations from Win Casino, freeware for Monte Carlo simulations in electron microscopy.



15 keV beam in Si, now he penetration is past 1 micrometer.



Oregon State University OSU Electron Microscopy Facility 30 keV beam incident on Si. We can see the dramatic increase in secondary electron volume. How many of these secondary's create X rays?





X ray volumes

- For production of X rays, we have to surpass the ionization potential for the x ray of choice.
- For Si, this would be at least 1.74 keV plus an overvoltage factor of 1.3. We need roughly 2.5 keV. Using an LET of 10 keV per micron, only the first 1.2 micron will create x rays.
- This is born out by irradiating polymers like Acrylic with 15 keV beams then etching the polymers to reveal the x ray volume.

Win Casino secondary electrons in blue, and approximate Si $K_{\alpha} x$ ray volume in red. 15 keV beam on Silicon.





SEM spot size spot 5 vs spot 1. Be warned effect on current is opposite than TEM. In SEM spot 5 is a large current and spot 1 is a smaller current that focuses better.



So, we should always be spot 5 for SEM EDS?



X ray process, Excite atom, electron falls from outer shell to inner shell to de-excite and x-ray is given off to conserve energy





Energy table for EDS analysis

http://www.jeol.com/



Series, there are two K transitions, α , β , γ^*

Atomic number 21, Titanium, 4s² not shown

Fe $K_{\alpha} K_{\beta}$



Peter Eschbach For reference, Goldstein, N

Oregon State

For reference, Goldstein, Newbury, Joy, Lyman, SEM and X-ray micro analysis.

Complete series vs atomic number. Important to realize that elements below A.N. 21 do not have L lines, and those below A.N. < 56* do not have M lines.



From Charlie Lyman's notes on STEM EDS, Lehigh short course 2010.

* Except In, Sn, Sb, and Te as those have promotion to f electron shells

Line Overlap in EDS

- This can affect quantitation
- Be aware of this and add S into the Quantitation if you have a Mo peak. Compute your wt% of Mo.
- Now delete the S and see if it makes a difference.
- Or you can use HPD in EDAX software, Deconvolution view in Bruker software or artificial spectra in Noran-Thermo Fisher software. This will find insufficient identifications and hidden peaks.
- There was a freeware program to find overlaps, beerware. It was free software that if you found useful you could buy the gentleman a beer at the annual Microscopy and Micro Analysis meeting.



In Moly Sulfide , the shoulder on Mo peak looks funny. It is actually an overlap of Mo and Sulfur.



Atomic transitions and characteristic line shapes



L

M series, heavy elements only, Tall and short. Don't confuse with K series of Sulfur or Phosphorous. Corroborate with higher energy L series that should be present!



Μ

Peter Eschbach

Oregon State University



Κ

Example with K,L,M,N lines



OSU Electron Microscopy Facility

Aside: What are the line strengths and why don't we see the Ky transition for example?

We see K_{α} and K_{β} from electron falling from n = 2 to n = 1 (L to K) and n = 3 to n = 1 (M to K) but why do we not see N to K transition or $K\gamma$?

The cross section for decay from higher energy shells is smaller, K_{α} to K_{β} is 10 to 1. The higher energy $K\gamma$ is allowed but is not visible because it so very weak.

Plausibility argument: Fermi's golden rule states the rate is proportional to Density of final state in K shell times density of states in N shell. With less DOS in K compared with N we get that the N to K shell transition is far less likely than the M to K transition β . For d electrons in the n = 4 state, l = 2. While the ground state is an S orbital with l = 0. This is not allowed by dipole selection rules l = +1,-1 and so the transition is forbidden and very slow depending upon quadrupole and higher terms that are small in comparison.



Identification strategies

- Use at least 20 keV, probably 30 keV for your first spectra.
- So often, students go straight from low keV imaging to EDS without increasing the energy. They then identify peaks based upon low energy only. Don't fall into this trap. Increase the keV so you can verify peaks.
- Start at the right side and identify the highest energy peaks. In this case Ta L series.
- Then go down and look for the M series in Ta. Or if you have identified the K series in Nickel, then go the left and identify the L series in Nickel.
- Higher atomic numbers should have K and L lines, and even more massive atoms have M and possibly N lines. Identify as many as you can.



Dead time and Pulse Pile Up

20% dead time, pulse pile up or sum peaks are unlikely



70% dead time, pulse pile up or sum peaks are frequently occurring

Most EDS systems in the last 10 years have digital pulse processing and can handle up to 60% dead time. But, just to make sure we keep dead time below 40%.



Red line denotes dead time

Consequences of too much Dead time, Pulse Pile Up or Sum Peaks.



You can turn on sum peaks in EDS and Noran software, turn them on and be wary of them.



Peter Eschbach

In some cases the Sum peaks can lead to mis-identifications: Argon, in an Aluminum sample? Probably not as Argon is a gas. Antimony, Sb in a Si sample? Both examples of Sum peaks, 2x energy. But there are more subtle peaks



This example from UW Madison showing a "Sulfur" peak. It is actually the sum peak of O .63 KeV and Si at 1.74 KeV!

Just keep your dead time below 40% and you probably will never see these. If you do see a "mysterium peak." Look at all possible sums.. Escape peak, Not readily observed on our systems with fairly thin detection areas, but here is what you should know about them.

- Higher energy x rays like Fe K or Pb L can induce fluorescence in the Si detector.
- Conservation of energy converts the Pb L to Pb L minus the Si K or 10.55 KeV – 1.74 KeV or 8.81 keV
- All you have to remember about escape peaks is minus 1.74 KeV. If you see a "mysterium peak" that is 1.74 keV below a strong, high energy peak it is an escape peak.





When in doubt over peak identifications, consult the known spectra that reside in the EDS software. These are found with the "HPD" button in EDAX, or "synthetic spectra" in the Noran-Thermo Fisher software.



"Point and shoot mode" in Noran – Thermo Fisher software. By clicking on the synthetic spectra in red, you can see that all of the peaks have been properly identified. In this case the ball of material, point one, of the failed part cross section is comprised mostly of Platinum.



Finally, a tricky situation. Running Quant routines you will get zero results on peaks that exist. In this 8000 year old Indian artifact spectra the Na was coming out zero but was clearly present. Upon further examination the background model, blue line, was clipping the spectra.



Peter Eschbach

Mapping, use max current, drift control (only on Quanta 3D) and do post process to background subtract.



This is a flip chip Ball Grid Array (BGA). Or how to make Hundreds of reliable interconnects in a small space. Example of vertical integration. All modern processors are BGA. That is, until the next innovation. Quanta 3D example. Pb-Sn solder ball on Aluminum traces on Silicon, Medtronik pacemaker, medical devices can still use Pb-Sn solder!

Same ball grid array, higher magnification now of just the surface of the Pb-Sn ball. Now notice the Cu streaks.

Peter Eschbach



Quantification or how we determine how much we have of every element. What we need for accurate quantification

- We must do accurate qualitative analysis first. Study line shapes on page 21 and use them! How else is the algorithm going to compute Absorbance and Fluorescence corrections if peaks in the sample are not identified or ignored. The famous one I get is: my sample doesn't have Na and Cl in it. Well, actually it does! And by ignoring those two elements you are degrading the accuracy of the quantitation.
- 2. Generally speaking we want to be above atomic number 11 for accurate quantification. This does not mean we can not get accurate quant on Oxygen. But we have to be careful and some of the tricks necessary for Carbon and Oxygen quantitation include, flat samples and standard checks to make sure the method is working.
- 3. Did I mention flat? If the sample is not flat, try tilting it towards the detector so that you are not sending X rays through topography.
- 4. Always run multiple spots and multiple KeV. At HP we had a rule for accurate quant: 3 locations and 2 keV. That is 6 measurements per sample. I know that many advisors give students 15 samples to analyze in limited time. But, on at least one of these, run 3 areas and 3 accelerating voltages: 15 keV and 30 keV to verify.
- 5. Standards. We have several standards from Tousimis and they are in the wood cabinets on the South side of the lab. Ask EM facility staff for one of these standards. There are up to 40 standards on one post so chances are we can find your compound and or something very close.





Quantification I, what is intensity?



Intensity is the total number of counts from Energy 1 to Energy 2. Or the Total Counts in a Region of Interest, ROI.



Peter Eschbach

Quantification I continued, how we use Intensity

- First order approximation: $C_i/C_{(i)} = I_i/I_{(i)} = k_{(i)}$ equation 9.3 Goldstein where C_i is concentration in the unknown, $C_{(i)}$ is the concentration in the standard. Method of Castaing, 1951
- For example, ROI from 1.70 to 1.78 keV defines Si. Measure intensity of a pure Silicon standard, then put unknown in. If you get 10% of the intensity from the background subtracted Si ROI, then sample is 10% Silicon correct?
- This technique will lead to errors in SEM because of absorption and fluorescence.
- That is heavier elements in the matrix will absorb x-rays from lighter and lighter elements will fluoresce from heavier element x-rays.
- See next page

Peter Eschbach Oregon State University



Downfall of Castaing's K factor approach

- Nickel K_{α} is higher energy than Fe and fluoresces Fe K_{α}
- And Fe will absorb Nickel K and so Nickel is diminished.
- When do K factors work?, TEM where sample is thin. Called Cliff-Lorimer method. K factor approach woefully in adequate for SEM.
- In SEM We use a series of three corrections of the K factor: Z for intensity difference due to different x ray yield, A for Absorbance say Iron absorbing Sulfur x-rays in a pyrite sample, and the final correction is due to fluorescence, F.



ZAF modification a second order more accurate determination than simple K factor of Castaing.

- $C_1/C_2 = \{ZAF\}I_1/I_2 = \{ZAF\}_1k_2$
- ZAF: Atomic number dependent stopping power and x-ray generation: Z, A for Absorption, F for Fluorescence
- Used in both EDS and WDS (electron microprobe analysis).
- Note a Z*A*F of less than one, typical for Si, Al, when heavier elements are in the material (matrix) ... drives the response down.
- Wt% Concentration = K factor/Z*A*F will see an example of this on next page



Standardless quant, ZAF, alloy OSU Q600 on EDAX software

- Si Wt% = k/Z*A*F = .0034/1.1459*.6295*1.0012 = .0047 or .47% exactly what is given below. QED*
- Similarly for Mo, [Mo] = .0079/.9007*.8922*1.0021 = .0098 or 9.8%
- And so it goes, lighter elements get enhanced by A <1 as they are attenuated by heavier elements and A is in the denominator.
- Heavier elements generally have A and Z close to one but have some action with Flourescence, Chromium has F of 1.12 and that drives the Chromium concentration down as there is strong Fluorescence of Cr by higher energy Fe and Mo x rays.



EDAX ZAF Quantification (Standardless) Element Normalized SEC Table : Default

Element	Wt %	At %	K-Ratio	Z	A	F
SiK	0.47	0.91	0.0034	1.1459	0.6295	1.0012
MoL	0.98	0.56	0.0079	0.9007	0.8922	1.0021
CrK	26.20	27.65	0.2916	0.9995	0.9950	1.1195
MnK	0.70	0.70	0.0068	0.9812	0.9981	1.0041
FeK	66.30	65.17	0.6525	0.9994	0.9795	1.0054
NiK	5.36	5.01	0.0517	1.0142	0.9518	1.0000
Total	100.00	100.00				



Quant Example II, Lab Standard Pyrite Notice A factor in Silicon, and Error in Si



This is the second case for an A of much less than unity in a light element. What does this do to the K factor?

EDAX ZAF Element SEC Tabl	'Quantif Normaliz .e : Defa	ication ed ult	(Standard	lless)		
Element	Wt %	At %	K-Ratio	Z	A	F
SiK S K FeK Total	0.86 52.72 46.42 100.00	1.22 65.61 33.17 100.00	0.0072 0.4984 0.4282	1.0692 1.0523 0.9327	0.7669 0.8968 0.9888	1.0168 1.0018 1.0000
Element	Net Int	e. Bk	gd Inte.	Inte. Ern	ror	P/B
SiK S K FeK	95.51 4900.93 1110.51		77.70 83.96 34.97	5.45 0.48 1.02		1.23 58.37 31.76



Peter Eschbach

Example III a glass sample



EDAX ZAF Quantification (Standardless) Element Normalized SEC Table : Default								
Element	Wt %	At 🖇	K-Ratio	Z	А	F		
O K MgK AlK SiK K K CrK FeK NiK Total	59.98 0.08 1.98 31.06 5.08 0.28 0.75 0.79 100.00	73.60 0.06 1.44 21.71 2.55 0.10 0.26 0.27 100.00	0.3134 0.0005 0.0154 0.2643 0.0447 0.0023 0.0064 0.0068	1.0235 0.9782 0.9472 0.9703 0.9216 0.8504 0.8471 0.8553	0.5103 0.7003 0.8117 0.8763 0.9551 0.9957 1.0005 1.0021	1.0003 1.0068 1.0124 1.0007 1.0004 1.0038 1.0036 1.0000		

Note, Concentration should be equal to the K ratio divided by ZAF:

Si example: K ratio .2643 Z = .9703, A = .8763, F = 1.0007 Wt% = .2643*100/(.9703*.8763*1.0007) = 31.06%

Fe example: K ratio .0064 Z = .8471, A = 1.0005, Z = 1.0036 Wt% Fe = .0064*100/(.8471*1.0005*1.0036) = 7.52%

Again, Z^*A^*F will drive up the concentration of a species as we know the response – x-rays- to this species will be lower.



Confidence in ZAF, standard less quantification method

- In many situations standardless quant in the SEM is superb for atomic numbers greater than 11. With an Iron Sulfite, pyrite, standard the EDAX, Si(Li) standard-less quant is typically within .2 At% of the correct answer, say 49.8% S and 50.2% Fe. With the Noran(SDD) and software the error is just a bit higher at say 49.4% and 50.6%.
- When in doubt, don't do standardless quant. Instead, use a sample that you have hard data on say from XPS. Then we can show you how to turn this into a standardized method!
- For a complete dissertation on the performance of standard-less quant see Goldstein Chapter 9. They quote 5% error for atomic numbers 12 and above.



STEM EDS, the ultimate spatial resolution



1 nm thin bilayer of MoS_2 film on SiO_2 with a Chrome protect layer. Conley group OSU

Oregon State University OSU Electron Microscopy Facility Peter Eschbach

TEM x-ray analysis

- Modern TEM's are generally a sandbox for analysis. You will have EDX and EELS on most. Some have cathode luminescence! You can also do diffraction. So, on hard problems we want to use all the tools. We don't want to just rely on TEM (STEM) EDS as it is not usually accurate enough for minor phase differences. That is we can't reliably tell In₂O₃ and InO phases. But, in diffraction we can distinguish those.
- In the TEM we put it in STEM mode do to the analysis. TEM mode floods the whole sample with the beam. We get an EDS signal but is from the whole sample. OK if your sample is homogenous but if you want small phases or thin film EDS, this is only done in STEM.





TEM quantification

- In TEM we can generally assume very little absorbance, very little fluorescence and stopping power and generation (Z) are approximately constant.
- Cliff-Lorimer realized that instead of ratio to a standard the response could be modelled by simply forming a ratio to subsequent peaks in the spectra.
- As such : $C_a/C_b = k_{ab}^*(I_a/I_b)$ its really the k factor approach of Castaing
- Manufacturer provides a table of Cliff-Lorimer factors, K_{ab} from calculation and some experimental data.
- But, for maximum accuracy in your quantification do create a binary standard of your compounds of interest and measure the response in your system.
- Note, for slightly thick samples, greater than 50 nm, absorption effects will drive down response of low atomic numbers. Some manufactures, Bruker allows you to input a "fudge factor" thickness and density that will correct for this. Or try a ZAF method.
- Because of the poor take off angle in a modern STEM, with a small gap in pole pieces absorption effects are actually substantial. In god we trust, for all others we strongly suggest standards.



OSU ChemiSTEM^{*} configuration, 4^{**} x-ray detectors at Φ, take off angle of 22 degrees.

Note, upper apertures in condenser create "hard", 17.4 keV, Moly x-rays that get to the sample and cause the TEM grid, often Cu to fluoresce Upper pole Collimator for unwanted pole piece x rays piece SDD x- ray detector Φ Because this is a high resolution instrument, Lower pole it has a narrow pole piece gap and so 22 piece degrees is it. A higher take off angle would be better for light element quantification! Scattered beam for Transmitted ChemiSTEM is a trademark of FEI Thermo Fisher it is not a scientific name Diffraction or EELS beam ** only 2 of the 4 detectors are pictured here





To projector lens and camera

Peter Eschbach

STEM EDS in TEM page 2

- When you look at the screen the 000 spot you see is a disk and its size is relative to the convergence angle on the sample. CA 100 (20 milli radian convergence) means big spot, CA 50 (10 milli radian convergence) smaller spot, CA 10 (2 milliard convergence) smallest spot.
- 2. When you pause the beam on a crystalline and look on the screen with the eye pieces you will notice many disks, Bragg diffraction. How can this be? It has to be that $\Theta_{HAADF} >> \Theta_{bragg}$. The Z contrast, HAADF, signal is actually from Rutherford backscattering and that is a much higher angle than Bragg scattering, roughly 10 milli rad for .3 nm d spacing (Si 111) and 200 keV electrons, $\lambda = .0025$ nm. The Howie (1979) detector or HAADF has $\Theta > 50$ milli rad to avoid Bragg Scattering and only pick up Atomic, Z contrast via high angle Rutherford scattering.
- Extra Credit! : By leaving the STEM scan on the OSU Titan and turning diffraction off you will actually see a shadow of the HAADF detector. The ray tracing for that is extra credit. Come see me if you get it and I will buy a cup of coffee for you at the OSU Ava's café.





EDS in TEM-STEM differences vs EDS in SEM

- Spatial resolution! STEM EDS in the TEM has 100 times the spatial resolution of SEM.
- The TEM sample is generally 100 nm thin and so beam scatter that reduces horizontal resolution is reduced. STEM EDS resolution is typically 1-2 nm at 200 keV.
- Take off angle can be poor relative to SEM and so quantification of light elements suffers. Thus, a need for standards when quant of light and heavy elements is needed.
- More fluorescence effects in TEM than SEM. Hard X-rays from the Molybdenum foil apertures at the top of the column.



TEM Spot number diagrams from the Titan manual, in a TEM we strengthen C1 at higher spot number and this is more de-magnification **and less current!**

3.4.1 Spot number

The user can choose from eleven settings for the image position of the first condenser lens (called spot number 1 to 11). The next two figures give each three sketches for the rays in these different settings for TEM and Probe mode. Increasing 'spot number' leads to increased demagnification of the source and to decreased current in the beam. Increasing the spot number by 1 leads to a reduction of the beam current by roughly 50%.



- Far left, spot 8 Condenser one is strongest and pulls crossover away from aperture underfilling and reducing current.
- Far right spot 1, Condenser one is weakest, this puts crossover nearer the aperture for near optimal filling and max current.
- Spot is a matter of preference. But, one thing to consider is beam coherence. Larger spot number on the TEM produces a more coherent beam and this can strengthen lattice fringes for example.
- For EDS maps, current is king, so spots less than 6 are typical.

OSU ChemiSTEM spectra. Proper alignment of all four detectors is key to good spectra on a multi detector instrument.

Before an alignment. A Satellite peak of Ni between where Co and Dy would be.



Post alignment Cr, Ni, Fe artificial spectra fits now with no satellite peaks.





Low energy peaks also improved by alignment of all 4 detectors.

- In the no spectra is ever quite perfect to us career EDS folks, there is an issue with the Carbon peak.
- Can you spot it? My colleague at U Hawaii, John Bradley did, and suggests it is in the Bruker Pulse processing method.
- Note, for better Carbon results in the Bruker software, use the max 60,000 cps option. This effectively increases the shaping time we spoke of in the introductory SEM EDS portion of this chapter, page 9. That should improve the low energy line shape.





The Cu Fluorescence from the Cu grid is ever present in a TEM sample. You can "deconvolve" the Cu from the spectra using Bruker software. This uses the known ratio of the k_{α} and k_{β} . Using a method with Cu identified but later "deconvolved" is the best practice.



In this case standardization was used to develop a method to quantify PbSe within .5% of the known stoichiometry. That result has been repeating for over one year on 30 plus samples.



Published result ₂ for DOE NETL on additive manufacturing. In this case the OSU Titan TEM was used to show NbOx layer and Alumina segregation in ceramic added to a high temperature steel.



Also, many peer reviewer's will ask for diffraction data to back up EDS data and a nice HAADF or TEM image as well!



2. <u>H Rao R. P.Oleksak^{ab}K. Favara^{ac}A/ Harooni^dB. Dutta^dD. Maurice^aBehavior of yttria-stabilized zirconia (YSZ) during laser direct energy deposition of an Inconel 625-YSZ cermet. Additive Manufacturing Vol 21, January 2020</u>

Other methods when EDS does not work.

Number 1 : EELS in STEM. Number 2 : XPS Number 3: WDS Number 4: ICP MS or ICP AES Number 5 and beyond: Accelerator techniques: PIXE, RBS (hydrogen), XANES (coordination number)



Peter Eschbach

EELS In this case it was used to confirm a Copper contamination, a tough one in EDS because of Bronze parts in TEM or Cu in the grid.



Peter Eschbach

X-ray Photo electron spectroscopy, XPS

- Escape depth of photo electron is first 30 Angstrom, 3 nm.
- So, you must have a freshly cleaved surface or do some in situ sputtering.
- TEM or STEM EDS is more bulk sensitive, first 30 nm
- In spite of these difficulties the agreement between XPS and STEM EDS linescans can be startlingly good. Many examples of this in my failure analysis background.
- XPS excels at Carbon to Oxygen ratio. STEM EDS fails at this because STEM environment is not nearly as clean as Ultra High Vacuum of an XPS.
- Compliment to EELS. UPS (XPS with ultra-violet source). EELS will sense empty states. XPS only observes occupied states.
- Auger and SIMS are similar but not quantitative. Although Auger has superior spatial resolution. SIMS has extreme sensitivity





WDS EDS resolution You can actually see the Sulfur K_{α} and K_{β} . This dramatically improves quantitation.



Oregon State University OSU Electron Microscopy Facilit

Peter Eschbach

Mass Spectroscopy techniques

- ICP-MS, accurate quantitation down to single ppm.
- ICP-AES is compliment for atoms that can't be detected in MS.
- It is destructive and has very little spatial resolution.
- GC MS and LC MS, if you can rinse your sample and extract stuff these two techniques will produce fantastic results as mass spectra will give you a fingerprint of the exact compound.
- MALDI TOF, Matrix Assisted Laser



Accelerator Techniques

PIXE: Particle Induced X –ray emission: few part per million sensitivities. Lateral width is 1-10 microns in well collimated accelerators. Atomic numbers greater than sodium.

Rutherford backscattering, RBS, use the proton beam to sense backscatter events and quantify light elements and it excels at Hydrogen.

Conclusion:

EDS and WDS are useful tools for characterization of materials. WDS was only briefly discussed as our facility does not have a WDS onsite. Quantification errors are surprisingly low with SEM EDS, errors only in the .2 Wt% for the Pyrite sample discussed. STEM EDS in a TEM has 100 times the spatial resolution of SEM EDS. STEM EDS is more tricky because of lower take off angles. Standardization of TEM EDS does result in very low errors, one half percent or less if the samples analyzed do resemble the standard. Finally, consider other methods. And that is a perfect lead into the next chapter, chapter 7, EELS.



Peter Eschbach